

Day : Friday

Date: 2/27/2004

Time: 16:44:33

PALM INTRANET

Inventor Name Search Result

Your Search was:

Last Name = HAN

First Name = QINGYUAN

Application#	Patent#	Status	Date Filed	Title	Inventor Name 18
60125616	Not Issued	159	03/22/1999	METHOD OF STRIPPING PHOTORESIST USING RE-COATING MATERIAL	HAN, QINGYUAN
10638570	Not Issued	020	08/11/2003	PLASMA ASHING PROCESS	HAN, QINGYUAN IFW - mine
10627894 2004002894	Not Issued	030	07/24/2003	FLUORINE-FREE PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	HAN, QINGYUAN IFW - mine
10623729 2004005519	Not Issued 1702	092 427/515	07/21/2003	ULTRAVIOLET CURING PROCESSES FOR ADVANCED LOW-K MATERIALS	HAN, QINGYUAN IFW - Pionato
10623712	Not Issued 1702	020 427/487	07/21/2003	LOW TEMPERATURE UV PRETREATING OF POROUS LOW-K MATERIALS	HAN, QINGYUAN IFW - unassigned
10413034 2003 0263217	Not Issued 1775	092 428/446	04/14/2003	HIGH MODULUS, LOW DIELECTRIC CONSTANT COATINGS all prod.	HAN, QINGYUAN IFW ← DIV 09/01/8,835
10384141 2003017755	Not Issued 1775	071 428/446	03/07/2003	PLASMA CURING PROCESS FOR POROUS SILICA THIN FILM all prod.	HAN, QINGYUAN IFW
10346560 2003015267	Not Issued 1702	030 427/489	01/17/2003	FLUORINE-FREE PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	HAN, QINGYUAN IFW - mine
10248707	Not Issued	030	02/11/2003	PLASMA ASHING PROCESS FOR REMOVING PHOTORESIST AND RESIDUES DURING FERROELECTRIC DEVICE FABRICATION	HAN, QINGYUAN
09952649	Not Issued	061	09/14/2001	PLASMA CURING PROCESS FOR POROUS LOW-K	HAN, QINGYUAN

				MATERIALS		
abd 21/7/04	09952398	Not Issued	060	09/14/2001	ULTRAVIOLET CURING PROCESS FOR POROUS LOW- K MATERIALS	HAN, QINGYUAN
X	09911682	6548416	150	07/24/2001	PLASMA <u>ASHING</u> PROCESS	HAN, QINGYUAN
this case	09906276	Not Issued	071	07/16/2001	PLASMA CURING OF MSQ- BASED POROUS LOW-K FILM MATERIALS	HAN, QINGYUAN
X	09855177	6630406	150	05/14/2001	PLASMA <u>ASHING</u> PROCESS	HAN, QINGYUAN
renew ODP	09681332	6558755	150	03/19/2001	PLASMA CURING PROCESS FOR POROUS SILICA THIN FILM	HAN, QINGYUAN
X	09531885	6406836	150	03/21/2000	METHOD OF <u>STRIPPING</u> PHOTORESIST USING RE- COATING MATERIAL	HAN, QINGYUAN
renew ODP	09528835	6576300	150	03/20/2000	HIGH MODULUS, LOW DIELECTRIC CONSTANT COATINGS	HAN, QINGYUAN
X	09368553	6281135	150	08/05/1999	OXYGEN FREE PLASMA <u>STRIPPING</u> PROCESS	HAN, QINGYUAN

Inventor Search Completed: No Records to Display.

Search Another: Inventor Last Name First Name

han qingyuan Search

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Inventor Name Search Result

Your Search was:

Last Name = HAN

First Name = QINGYAUN

Application#	Patent#	Status	Date Filed	Title	Inventor Name 1
10065861	Not Issued	030 1764	11/26/2002 134/420	<i>growing ???</i> DRYING PROCESS FOR LOW-K DIELECTRIC FILMS	HAN, QINGYAUN IFW

Inventor Search Completed: No Records to Display.

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han	qingyaun	Search

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Day : Friday
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Inventor Name Search Result

Your Search was:

Last Name = BERRY

First Name = IVAN

(Handwritten notes on the left margin: "PRO" with a bracket for the first five rows, and "w/HQ" repeated for the last seven rows.)

Application#	Patent#	Status	Date Filed	Title	Inventor Name 33
<u>60125616</u>	Not Issued	159	03/22/1999	METHOD OF STRIPPING PHOTORESIST USING RE-COATING MATERIAL	BERRY, IVAN
<u>60120866</u>	Not Issued	159	02/19/1999	METHOD OF PHOTORESIST ASH RESIDUE REMOVAL	BERRY, IVAN
<u>60072139</u>	Not Issued	159	01/22/1998	PROGRAMMABLE APERTURE PLATE FOR HIGH THROUGHPUT SUB 0.1 UM LITHOGRAPHY	BERRY, IVAN L.
<u>60055052</u>	Not Issued	159	08/08/1997	PROGRAMMABLE APERTURE PLATE FOR HIGH THROUGHOUT SUB 0.1 UM LITHOGRAPHY	BERRY, IVAN L.
<u>60036354</u>	Not Issued	159	01/23/1997	PROGRAMMABLE APERTURE PLATE FOR HIGH THROUGHPUT SUB 0.1 UM LITHOGRAPHY	BERRY, III, IVAN L.
<u>10627894</u>	Not Issued	030	07/24/2003	FLUORINE-FREE PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	BERRY, IVAN L.
<u>10623729</u>	Not Issued	092	07/21/2003	ULTRAVIOLET CURING PROCESSES FOR ADVANCED LOW-K MATERIALS	BERRY, IVAN L.
<u>10623712</u>	Not Issued	020	07/21/2003	LOW TEMPERATURE UV PRETREATING OF POROUS LOW-K MATERIALS	BERRY, IVAN L.
<u>10413034</u>	Not Issued	092	04/14/2003	HIGH MODULUS, LOW DIELECTRIC CONSTANT COATINGS	BERRY, IVAN LOUIS
<u>10384141</u>	Not Issued	071	03/07/2003	PLASMA CURING PROCESS FOR POROUS SILICA THIN FILM	BERRY, IVAN L.
<u>10346560</u>	Not	030	01/17/2003	FLUORINE-FREE PLASMA	BERRY, IVAN L.

	Issued			CURING PROCESS FOR POROUS LOW-K MATERIALS	
<i>app</i> X 10336270	6673197	150	01/03/2003	CHEMICAL PLASMA CATHODE	BERRY, IVAN
<i>W/HQ</i> <u>10248779</u>	Not Issued	071	02/18/2003 ?	PROCESS FOR OPTICALLY ERASING CHARGE BUILDUP DURING FABRICATION OF AN INTEGRATED CIRCUIT	BERRY, IVAN
<i>W/HQ</i> 10065861	Not Issued	030	11/26/2002	DRYING PROCESS FOR LOW- K DIELECTRIC FILMS	BERRY, IVAN
<i>W/HQ</i> <u>10064219</u>	<u>6664737</u>	150	06/21/2002 ?	DIELECTRIC BARRIER DISCHARGE APPARATUS AND PROCESS FOR TREATING A SUBSTRATE	BERRY, IVAN
<u>10004523</u>	Not Issued	071	11/01/2001 ?	PLASMA PROCESS AND APPARATUS	BERRY, IVAN
10000772	<u>6605484</u>	150	11/30/2001	PROCESS FOR OPTICALLY ERASING CHARGE BUILDUP DURING FABRICATION OF AN INTEGRATED CIRCUIT	BERRY, IVAN
<i>N/HQ</i> <u>09952649</u>	Not Issued	061	09/14/2001	PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	BERRY, IVAN L.
<i>N/HQ</i> <u>09952398</u>	Not Issued	060	09/14/2001	ULTRAVIOLET CURING PROCESS FOR POROUS LOW- K MATERIALS	BERRY, IVAN L.
<i>N/HQ</i> X <u>09911682</u>	6548416	150	07/24/2001	PLASMA ASHING PROCESS	BERRY, IVAN
<i>N/HQ</i> <u>09906276</u>	Not Issued	071	07/16/2001	PLASMA CURING OF MSQ- BASED POROUS LOW-K FILM MATERIALS	BERRY, IVAN L.
<i>N/HQ</i> X <u>09876318</u>	6638875	150	06/07/2001	OXYGEN FREE PLASMA STRIPPING PROCESS	BERRY, IVAN
<i>N/HQ</i> X <u>09864003</u>	Not Issued	061	05/23/2001	PLASMA PROCESS FOR REMOVING POLYMER AND RESIDUES FROM SUBSTRATES	BERRY, IVAN
<i>N/HQ</i> X <u>09855177</u>	6630406	150	05/14/2001	PLASMA ASHING PROCESS	BERRY, IVAN
<i>N/HQ</i> X <u>09732064</u>	6503366	150	12/07/2000	CHEMICAL PLASMA CATHODE	BERRY, IVAN
<i>N/HQ</i> <u>09681332</u>	<u>6558755</u>	150	03/19/2001	PLASMA CURING PROCESS FOR POROUS SILICA THIN FILM	BERRY, IVAN L.
<i>N/HQ</i> X <u>09543373</u>	Not	161	04/02/2000	POST ETCH PHOTORESIST	BERRY, IVAN

	Issued			AND <u>RESIDUE REMOVAL</u> PROCESS	
<u>09531885</u>	<u>6406836</u>	150	03/21/2000	METHOD OF <u>STRIPPING</u> PHOTORESIST USING RE- COATING MATERIAL	BERRY, IVAN
<u>09528835</u> ✓	<u>6576300</u>	150	03/20/2000	HIGH MODULUS, LOW DIELECTRIC CONSTANT COATINGS	BERRY III, IVAN LOUIS
<u>09505695</u>	Not Issued	093	02/17/2000	METHOD OF PHOTORESIST <u>ASH RESIDUE REMOVAL</u>	BERRY, IVAN
<u>09368553</u> X	<u>6281135</u>	150	08/05/1999	OXYGEN FREE PLASMA STRIPPING PROCESS	BERRY , IVAN
<u>09137504</u>	<u>6300017</u>	150	08/20/1998	STENCIL MASKS AND METHODS OF MANUFACTURING STENCIL MASKS	BERRY , IVAN L.
<u>06561747</u>	<u>4631704</u>	150	12/15/1983	METHODS AND DEVICES FOR CHARGED BEAM <u>ACCESSIBLE DATA STORAGE</u>	BERRY , IVAN L.

Inventor Search Completed: No Records to Display.

	Last Name	First Name	
Search Another: Inventor	berry	ivan	<input type="button" value="Search"/>

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Inventor Name Search Result

Your Search was:

Last Name = WALDFRIED

First Name = CARLO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 18
10638570	Not Issued	020	08/11/2003	PLASMA <u>ASHING</u> PROCESS	WALDFRIED, CARLO
10627894	Not Issued	030	07/24/2003	FLUORINE-FREE PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	WALDFRIED, CARLO
10623729	Not Issued	092	07/21/2003	ULTRAVIOLET CURING PROCESSES FOR ADVANCED LOW-K MATERIALS	WALDFRIED, CARLO
10623712	Not Issued	020	07/21/2003	LOW TEMPERATURE UV PRETREATING OF POROUS LOW-K MATERIALS	WALDFRIED, CARLO
10384141	Not Issued	071	03/07/2003	PLASMA CURING PROCESS FOR POROUS SILICA THIN FILM	WALDFRIED, CARLO
10346560	Not Issued	030	01/17/2003	FLUORINE-FREE PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	WALDFRIED, CARLO
10249962	Not Issued	030	05/22/2003	PLASMA APPARATUS, GAS DISTRIBUTION ASSEMBLY FOR A PLASMA APPARATUS AND PROCESSES THEREWITH	WALDFRIED, CARLO
10248707	Not Issued	030	02/11/2003	PLASMA <u>ASHING</u> PROCESS FOR REMOVING PHOTORESIST AND RESIDUES DURING FERROELECTRIC DEVICE FABRICATION	WALDFRIED, CARLO
10065861	Not Issued	030	11/26/2002	DRYING PROCESS FOR LOW-K DIELECTRIC FILMS	WALDFRIED, CARLO

W/HQ	09952649 ✓	Not Issued	061	09/14/2001	PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	WALDFRIED, CARLO
W/HQ	09952398 abd	Not Issued	060	09/14/2001	ULTRAVIOLET CURING PROCESS FOR POROUS LOW-K MATERIALS	WALDFRIED, CARLO
W/HQ	09911682 X	6548416	150	07/24/2001	PLASMA ASHING PROCESS	WALDFRIED, CARLO
Shoensee	09906276	Not Issued	071	07/16/2001	PLASMA CURING OF MSQ- BASED POROUS LOW-K FILM MATERIALS	WALDFRIED, CARLO
X	09864003	Not Issued	061	05/23/2001	PLASMA PROCESS FOR REMOVING POLYMER AND RESIDUES FROM SUBSTRATES	WALDFRIED, CARLO
W/HQ X	09855177	6630406	150	05/14/2001	PLASMA ASHING PROCESS	WALDFRIED, CARLO
W/HQ	09681332 ✓	6558755	150	03/19/2001	PLASMA CURING PROCESS FOR POROUS SILICA THIN FILM	WALDFRIED, CARLO
	09543373	Not Issued	161 abd	04/02/2000	POST ETCH PHOTORESIST AND RESIDUE REMOVAL PROCESS	WALDFRIED, CARLO
X	09114999	6184523	150	07/14/1998	HIGH RESOLUTION CHARGED PARTICLE- ENERGY DETECTING, MULTIPLE SEQUENTIAL STAGE, COMPACT, SMALL DIAMETER, RETRACTABLE CYLINDRICAL MIRROR ANALYZER SYSTEM, AND METHOD OF USE	WALDFRIED, CARLO

Inventor Search Completed: No Records to Display.

	Last Name	First Name	
Search Another: Inventor	<input type="text" value="waldfried"/>	<input type="text" value="carlo"/>	<input type="button" value="Search"/>

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Inventor Name Search Result

Your Search was:

Last Name = ESCORCIA

First Name = ORLANDO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 12
10638570 X	Not Issued	020	08/11/2003	PLASMA ASHING PROCESS	ESCORCIA, ORLANDO
10627894	Not Issued	030	07/24/2003	FLUORINE-FREE PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	ESCORCIA, ORLANDO
10623729	Not Issued	092	07/21/2003	ULTRAVIOLET CURING PROCESSES FOR ADVANCED LOW-K MATERIALS	ESCORCIA, ORLANDO
10623712	Not Issued	020	07/21/2003	LOW TEMPERATURE UV PRETREATING OF POROUS LOW-K MATERIALS	ESCORCIA, ORLANDO
10346560	Not Issued	030	01/17/2003	FLUORINE-FREE PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	ESCORCIA, ORLANDO
10248707 x	Not Issued	030	02/11/2003	PLASMA ASHING PROCESS FOR REMOVING PHOTORESIST AND RESIDUES DURING FERROELECTRIC DEVICE FABRICATION	ESCORCIA, ORLANDO
10065861	Not Issued	030	11/26/2002	DRYING PROCESS FOR LOW-K DIELECTRIC FILMS	ESCORCIA, ORLANDO
09952649 ✓	Not Issued	061	09/14/2001	PLASMA CURING PROCESS FOR POROUS LOW-K MATERIALS	ESCORCIA, ORLANDO
09952398 abd	Not Issued	060	09/14/2001	ULTRAVIOLET CURING PROCESS FOR POROUS LOW-K MATERIALS	ESCORCIA, ORLANDO
09906276 this case	Not Issued	071	07/16/2001	PLASMA CURING OF MSQ-BASED POROUS LOW-K FILM MATERIALS	ESCORCIA, ORLANDO

w/cw
w/HQ

<u>09864003</u> A	Not Issued	061	05/23/2001	PLASMA PROCESS FOR REMOVING POLYMER AND RESIDUES FROM SUBSTRATES	ESCORCIA, ORLANDO
<u>09855177</u> X	6630406	150	05/14/2001	PLASMA ASHING PROCESS	ESCORCIA, ORLANDO

Inventor Search Completed: No Records to Display.

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